

	Application No.	Applicant(s)
Mating of Allowshiller	10/677,008	ZHANG ET AL.
Notice of Allowability	Examiner	Art Unit
	Renee R. Berry	2829
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. This communication is responsive to <u>12/23/04</u> .		
2. ☑ The allowed claim(s) is/are <u>1-3,5 and 8-20</u> .		
3. ☑ The drawings filed on <u>30 September 2003</u> are accepted by the Examiner.		
 4. Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a)		
Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date	6. ☐ Interview Summary Paper No./Mail Dat 98), 7. ☐ Examiner's Amendr	te

REASONS FOR ALLOWANCE

The following is an examiner's statement of reasons for allowance: There is no prior art of record that teaches or suggests a method of dry etching a PCMO stack by etching the PCMO layer includes a two-step etching process, wherein the first etching step includes etching the PCMO layer using a gas mixture of argon, oxygen, and a gas taken from the group of gases consisting of Cl₂, BCl₂, CCl₄, SiCl₄, and a combination thereof, wherein the percentage of the oxygen is in a range of between about 1% to 50%, in a preferred range of between about 5% to 30%; the percentage of argon is in a range of between about 5% to 80%, and in a preferred range of between about 40% to 80%; and wherein the remaining gas component consists of a Cl-containing gas, and which further includes providing a gas flow rate of between about 20 sccm to 100sccm.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Renee R. Berry whose telephone number is (571) 272-1774. The examiner can normally be reached on M-F 9-5:30.

The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Application/Control Number: 10/677,008

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

RRB

March 21, 2005

Bavid Nelms
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